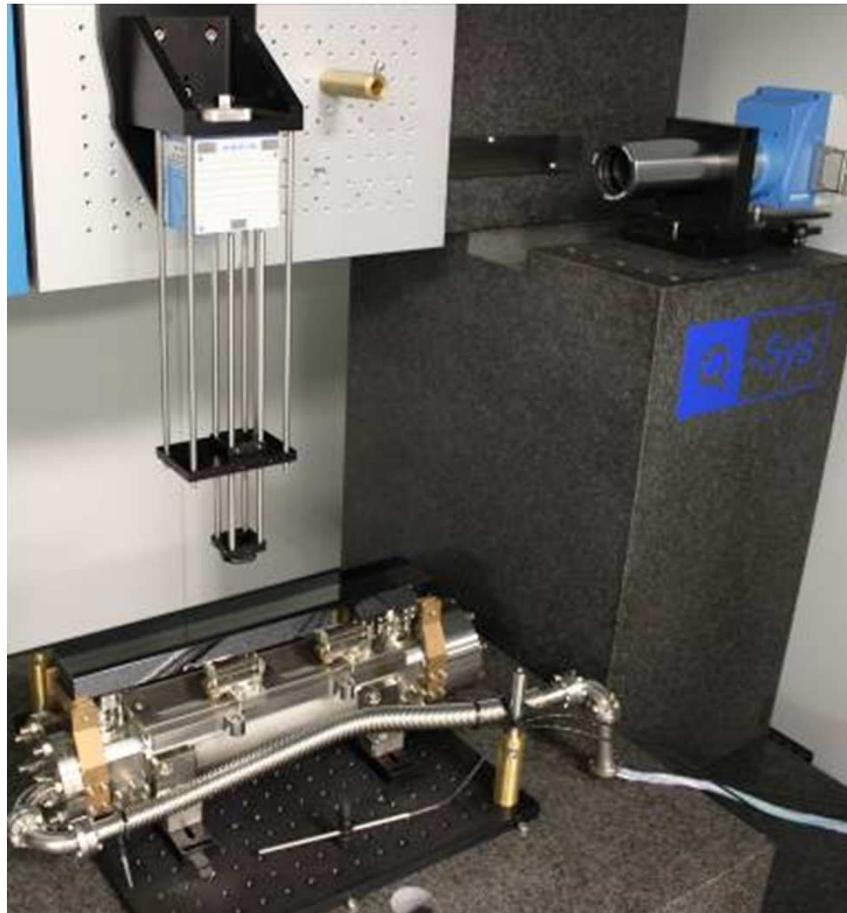




# Characterization of the error budget of the Alba-NOM

Josep Nicolas, Juan Carlos Martínez  
ALBA light source

We aim to characterize the uncertainty of slope measurements obtained by the Alba-NOM, contributed by stochastic effects and systematic errors:



## 1. The bench

- a. Motion metrology
- b. Raytracing of the guidance induced error
- c. Vibrations, noise and stability

## 2. The optics

- a. Calibration using redundant-independent datasets.
- b. Optimization of the iris aperture.

## 3. One application

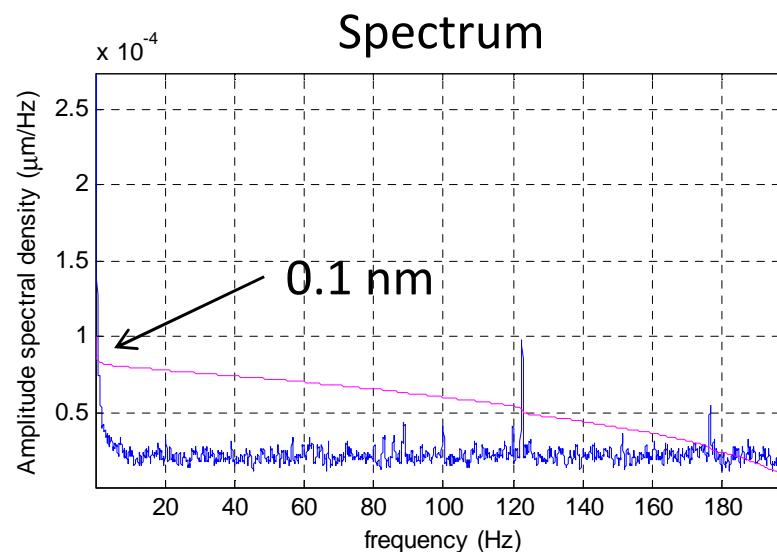
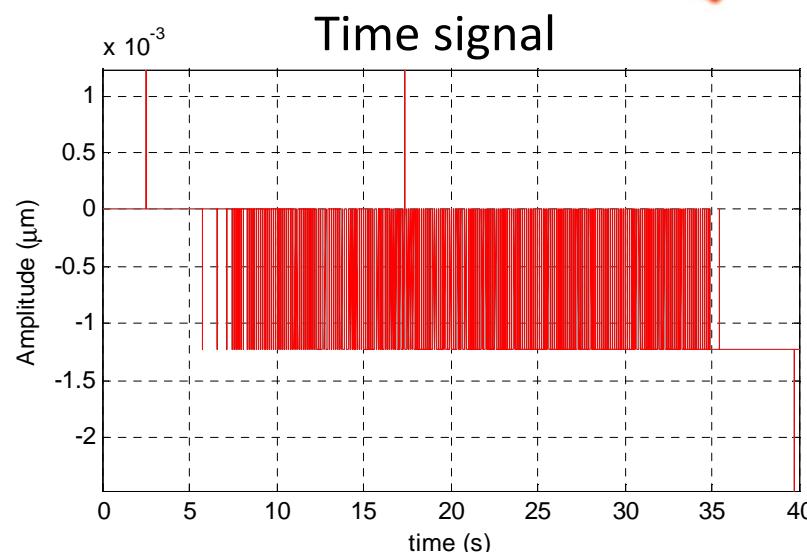
- a. surface correction using few point forces
- b. Exsitu vs Insitu

# Motion performance

The use of a differential interferometer allows an accurate characterization of the motion performance of the bench



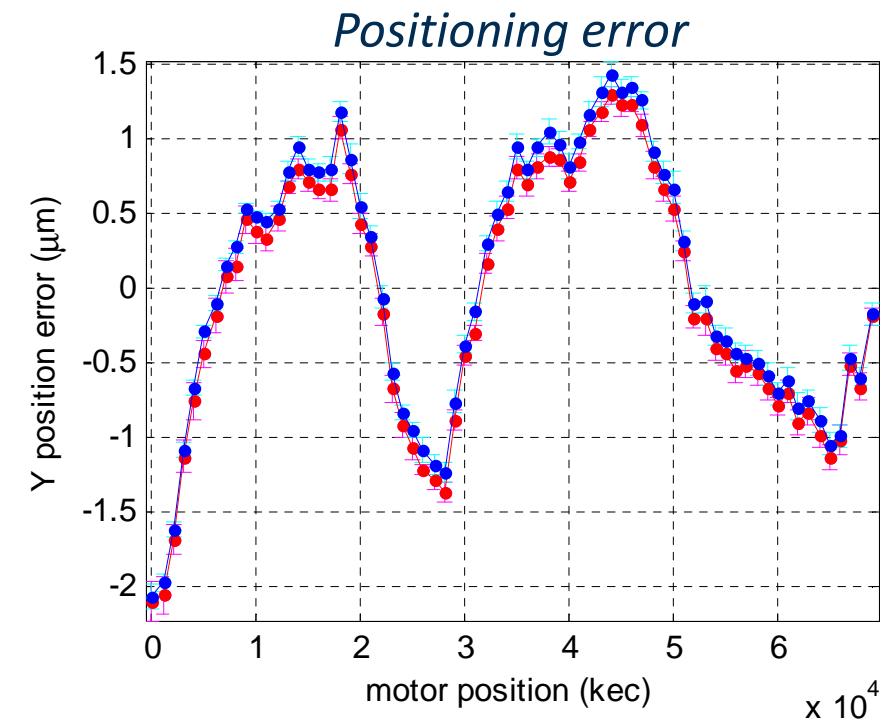
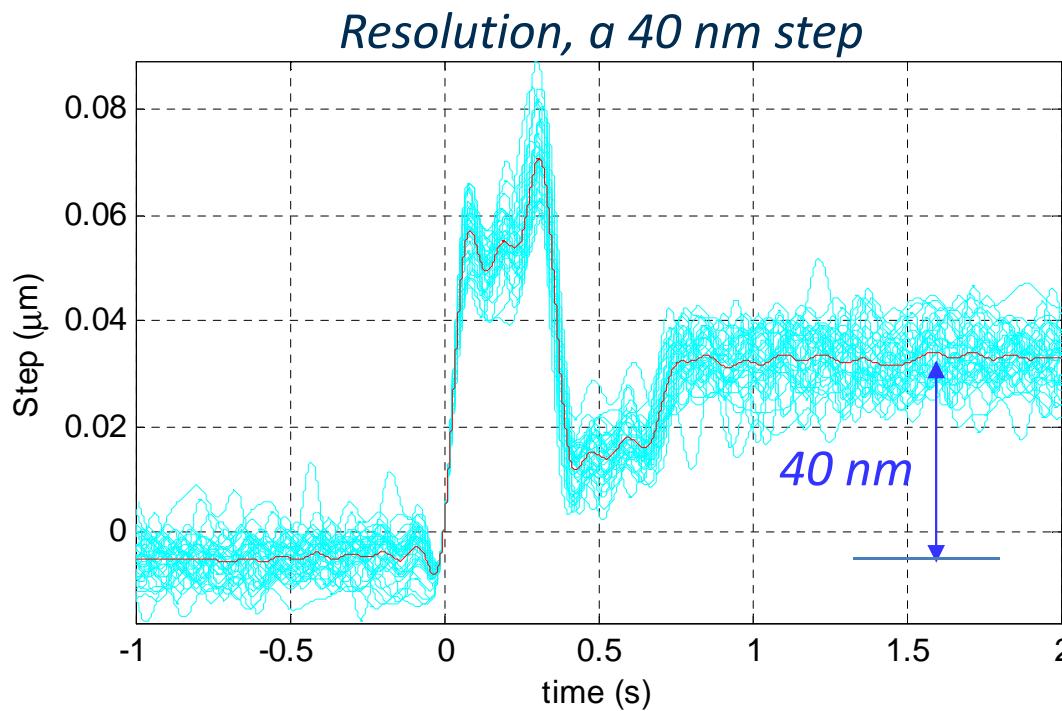
<i>Resolution (linear)</i>	1 nm
<i>Resolution (angular)</i>	41 nrad
<i>Maximum sampling rate</i>	5 kHz
<i>Noise level</i>	~0.1 nm RMS
<i>Accuracy (linear)</i>	±0.7 p.p.m
<i>Linearity (angular)</i>	±0.5 µrad



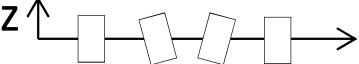
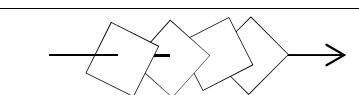
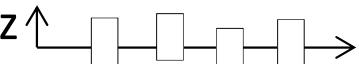
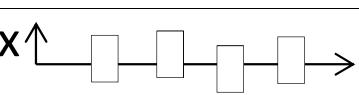
# Motion performance

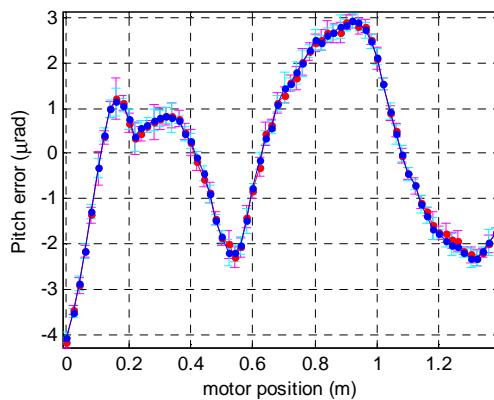
The use of a differential interferometer allows an accurate characterization of the motion performance of the bench

	Backlash	Accuracy	Repeatability	Resolution
Position	100 nm	3.5 um	77 nm	20 nm

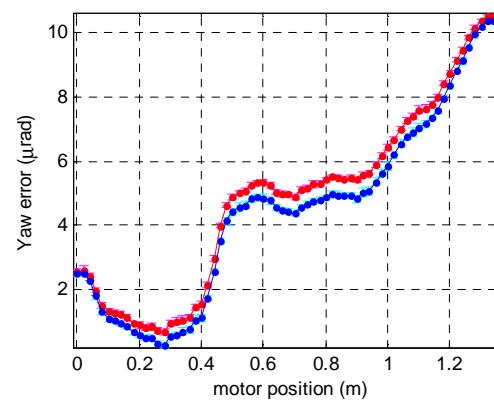


# Guidance measurements

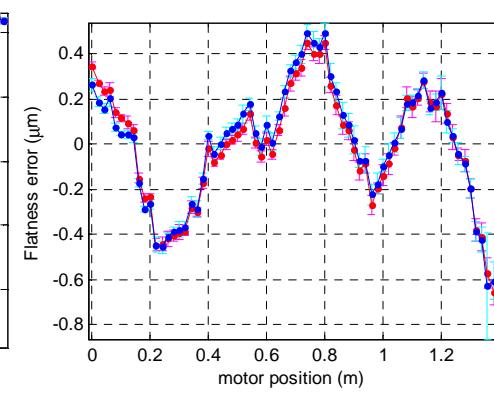
	Backlash	Accuracy	Repeatability
pitch	z ↑ 	2 nrad	7.1 urad
yaw	x ↑ 	390 nrad	10.1 urad
roll		<115 nrad	6.1 urad
flatness	z ↑ 	14 nm	1.1 um
straightness	x ↑ 	2 nm	2.1 um



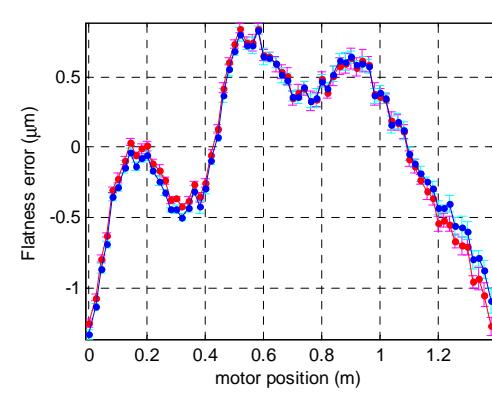
*Pitch*



*Yaw*

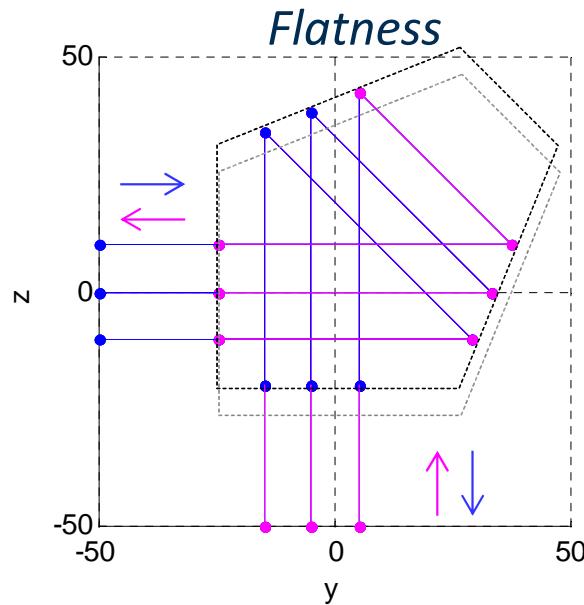
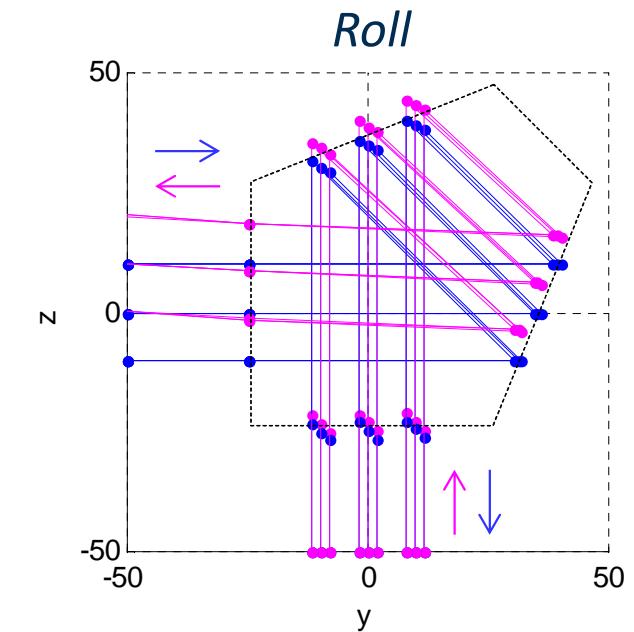
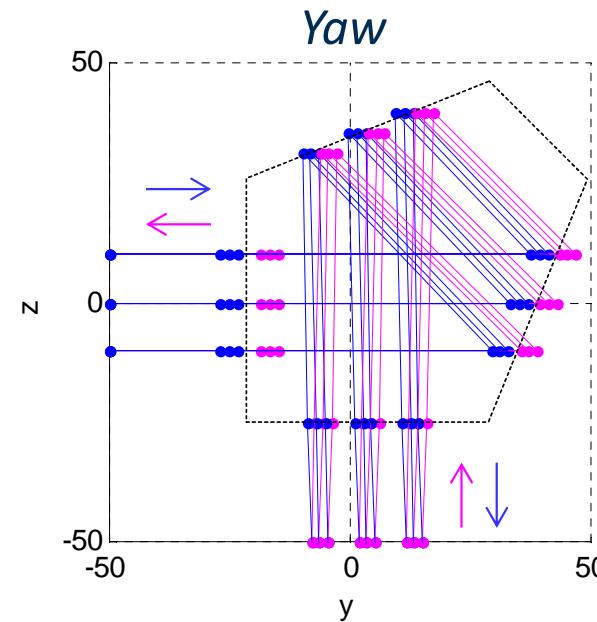
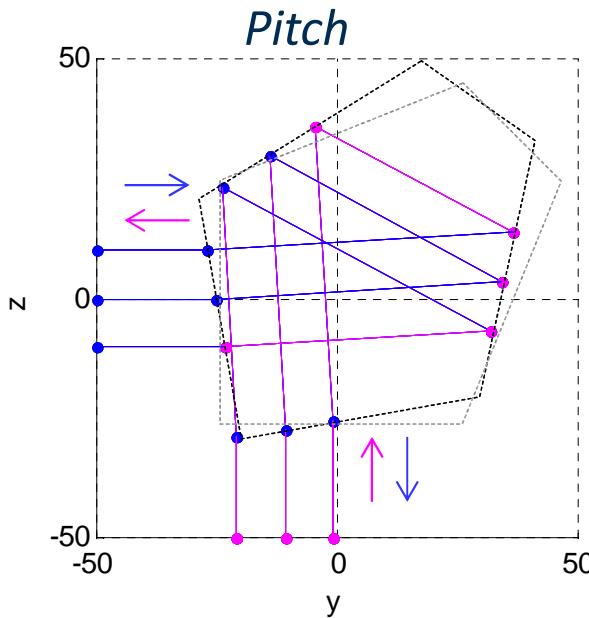


*Flatness*



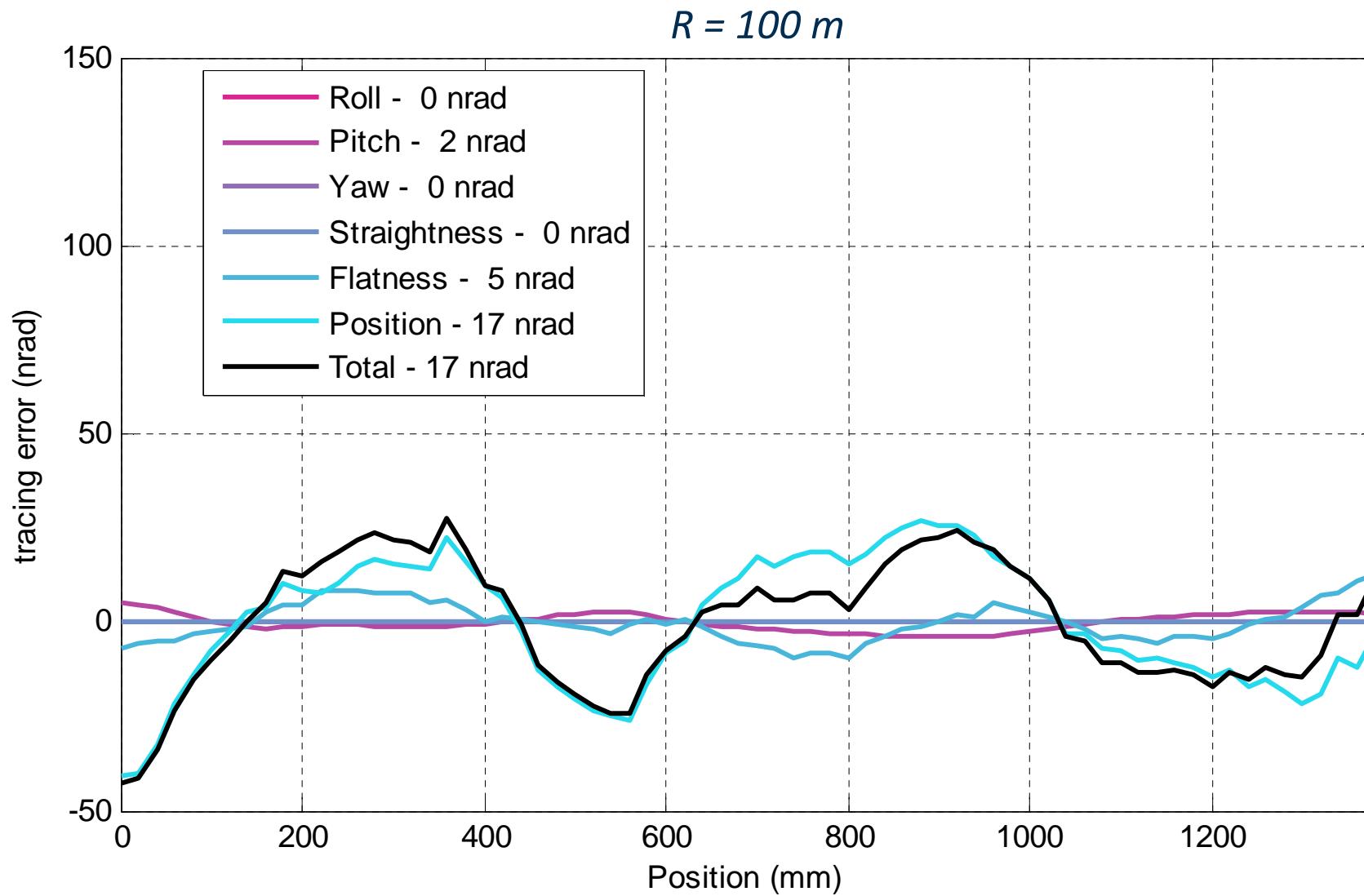
*Straightness*

# Raytracing



*Double pass raytracing of the scanning pentaprism is used to determine the influence of guidance error on the measurement*

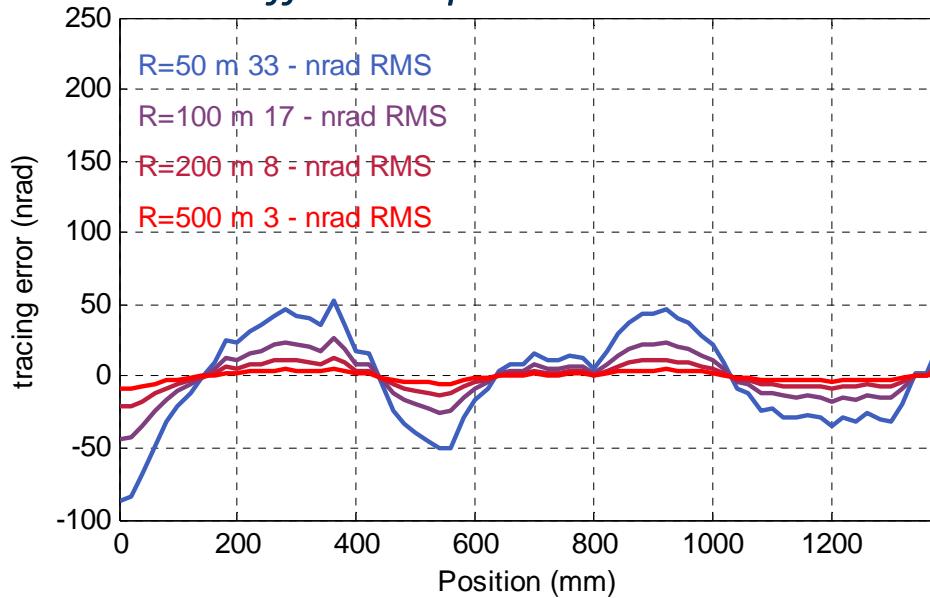
# Guidance accuracy



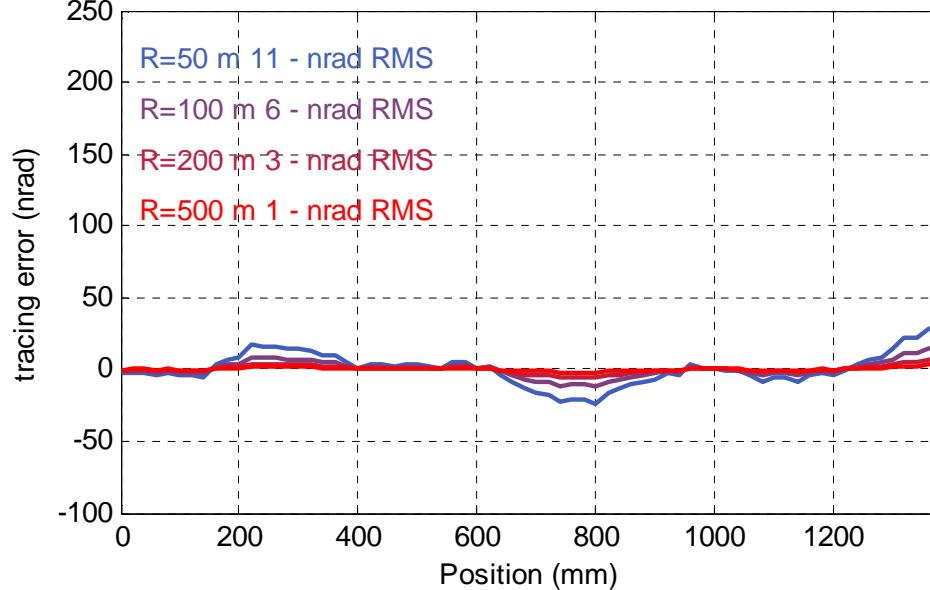
*Contribution of the guidance error to the LTP error*

# Guidance accuracy

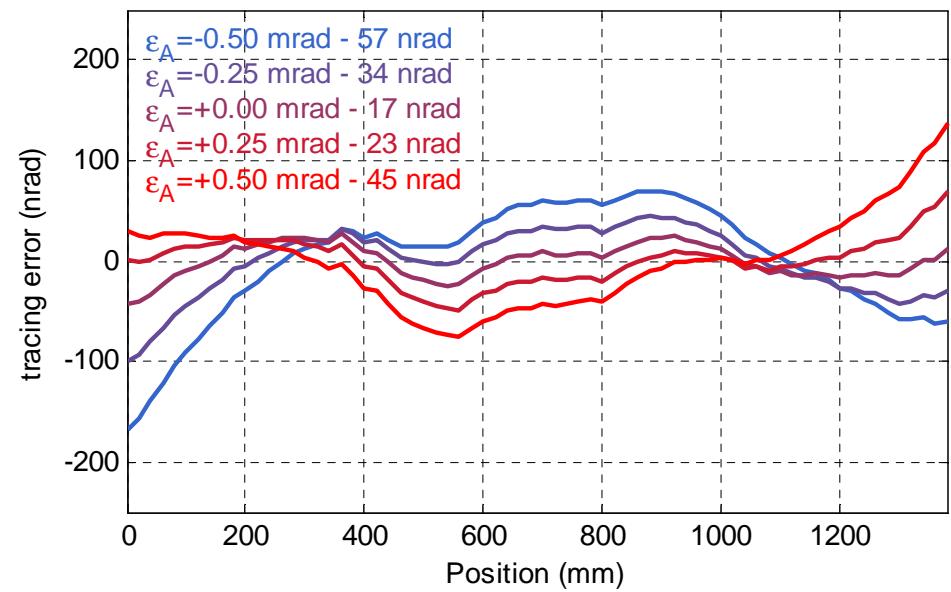
*Different spheres*



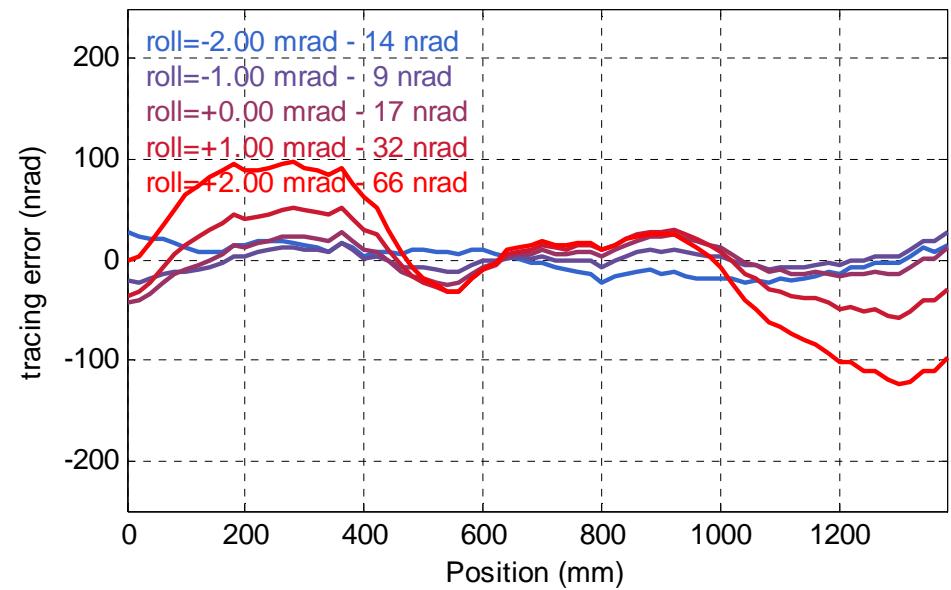
*Different spheres – Position LUT*



*Pentaprism error – R=100 m*

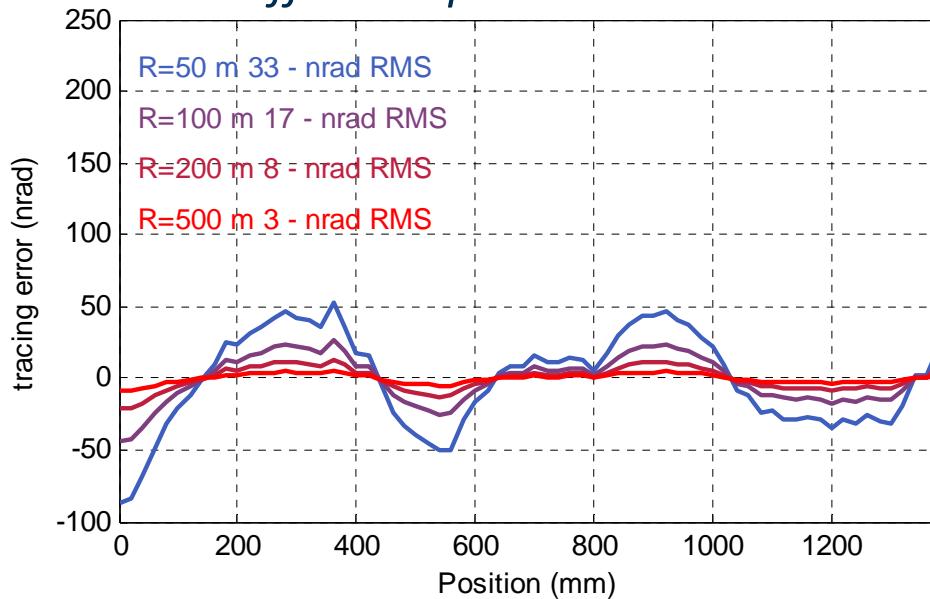


*Pentaprism roll – R=100 m*

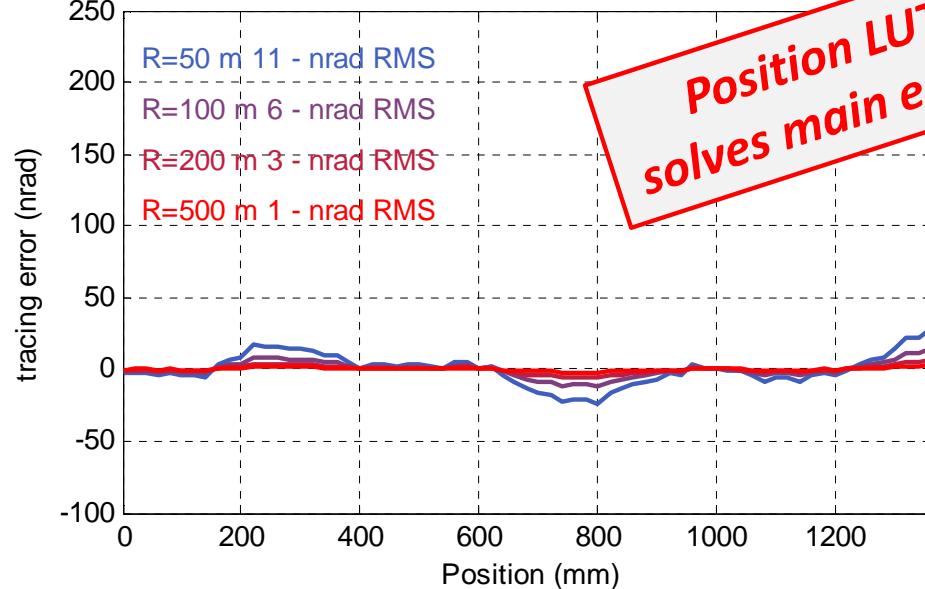


# Guidance accuracy

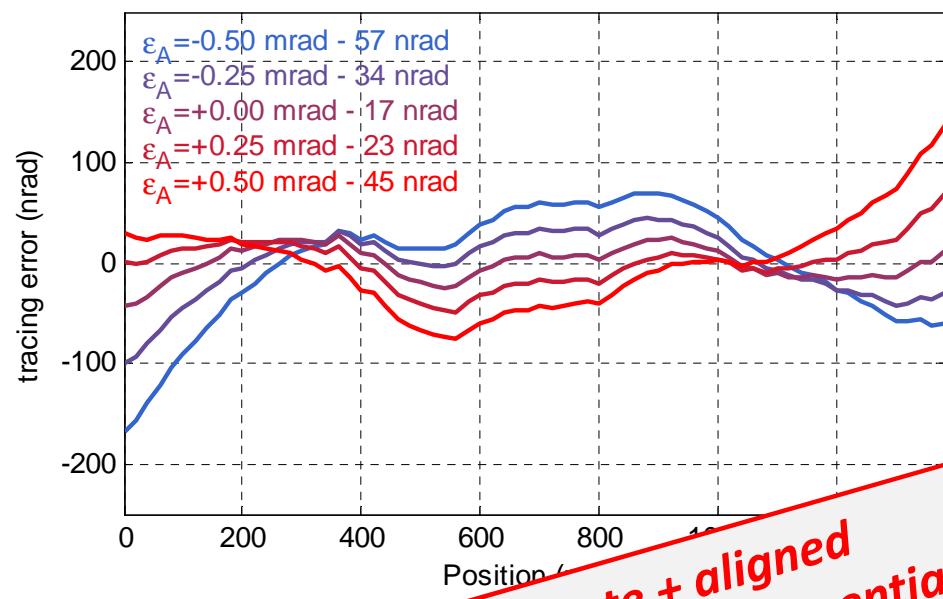
*Different spheres*



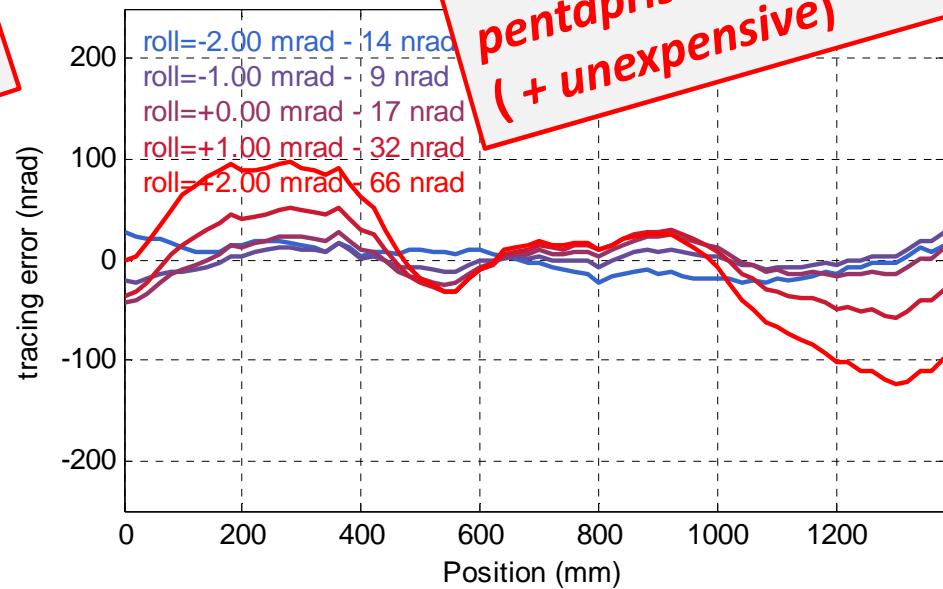
*Different spheres – Position LUT*



*Pentaprism error – R=100 m*

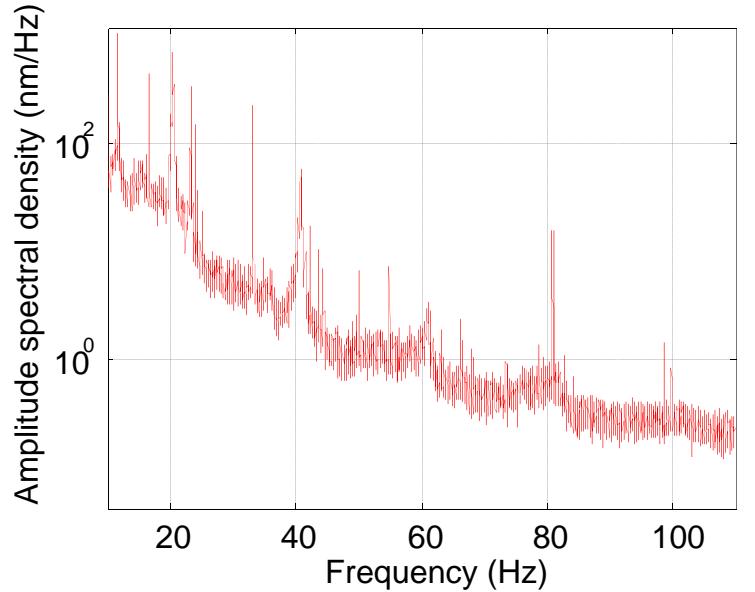


*Pentaprism*

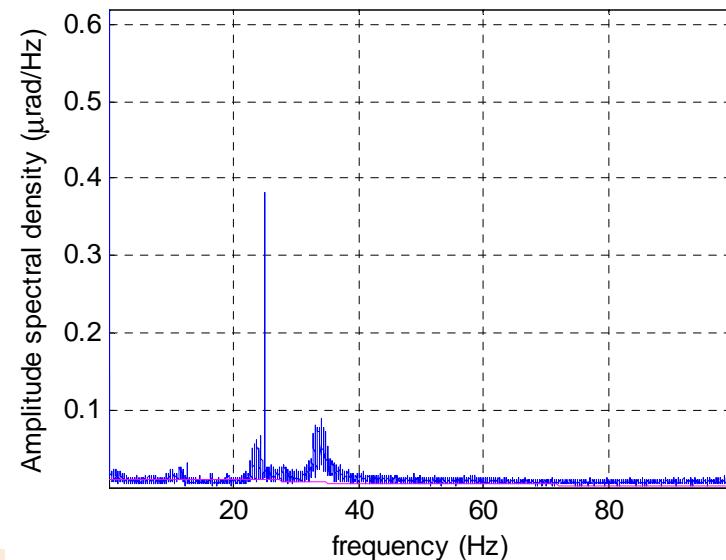
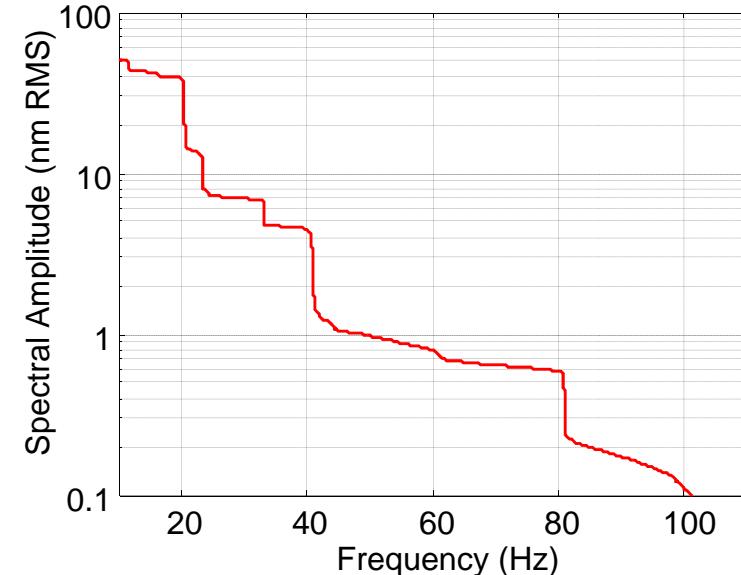


# Vibrations on top of the NOM

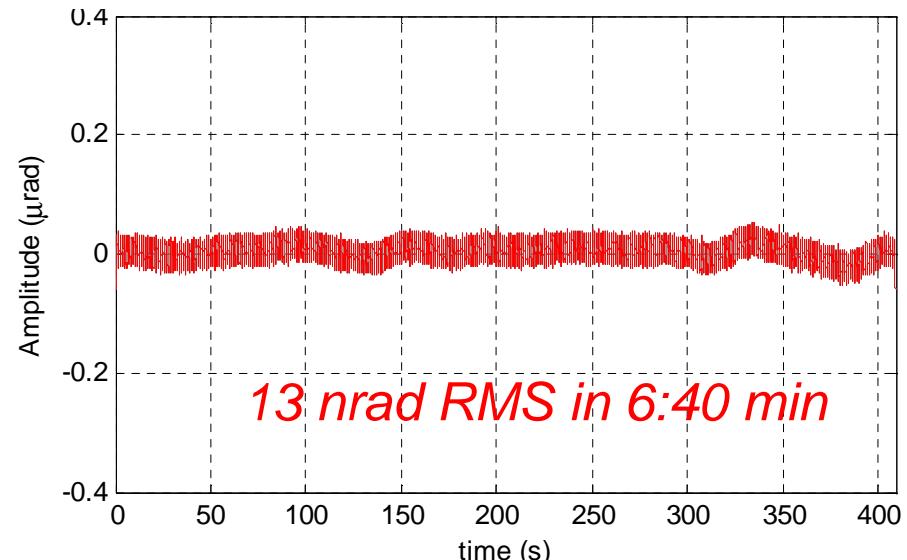
Although the amplitude of the vibration in the ground is **50 nm RMS**, the measurement on top of the NOM is **13 nrad RMS**



← *Ground vibration (vertical)* →



← *NOM → (pitch between platforms)* →



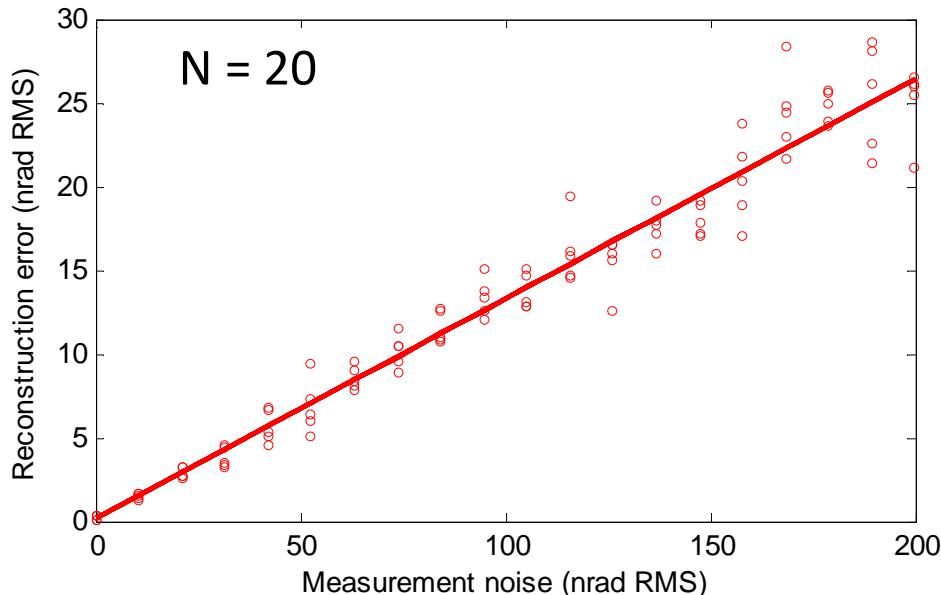
# Redundant-independent datasets

The use of redundant-independent measurements of a mirror allows to estimate the slope error and the linearity error of the instrument

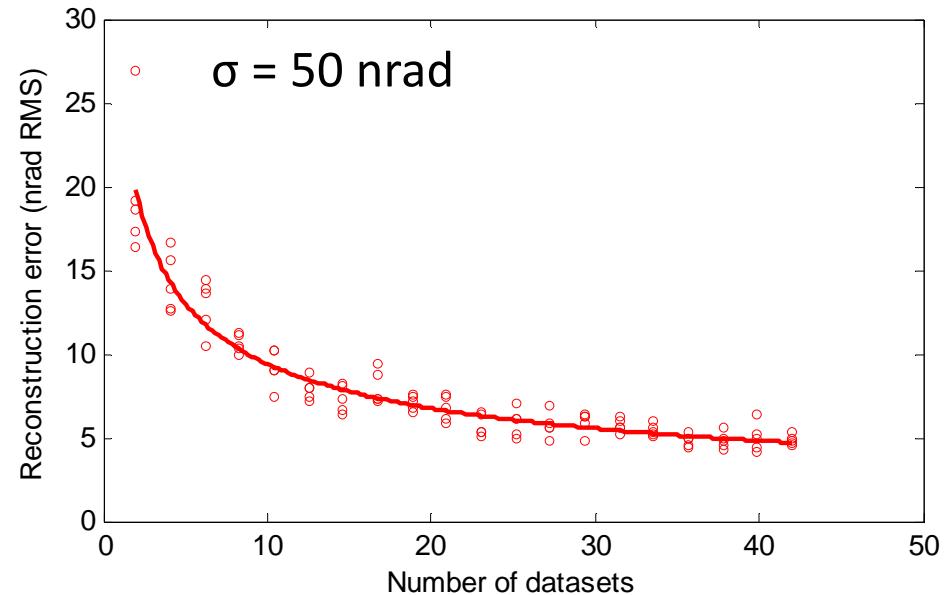
The resolution of the surface is limited

- Validity of the error model → short mirrors vs long mirrors
- Noise of each measurement
- Number of measurements

Simulation: accuracy dependence on noise



Simulation: accuracy dependence on number of datasets

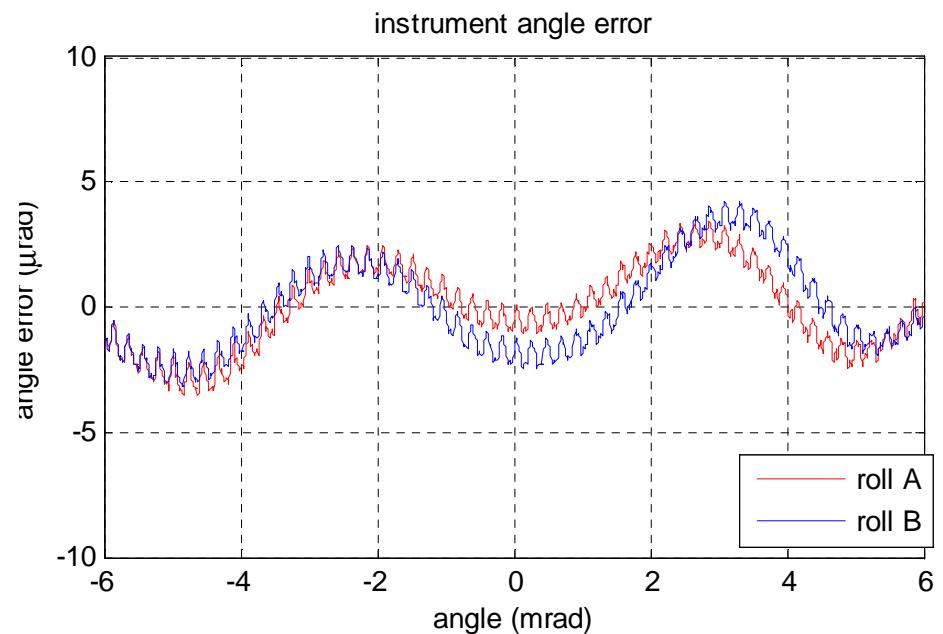
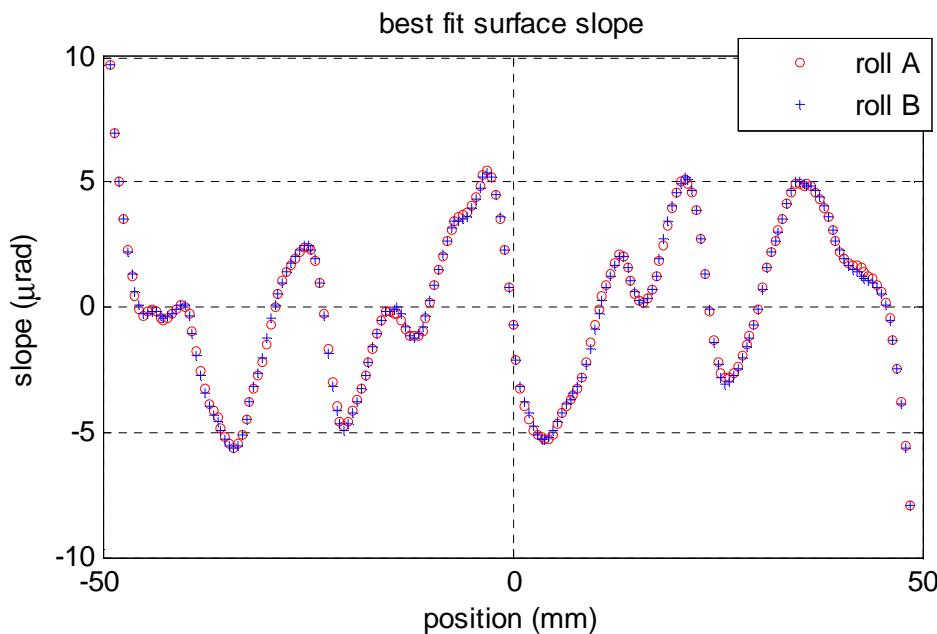


# Redundant-independent datasets

A 100 mm,  $R=75$  m sphere has been used to cover 12 mrad range of the NOM.

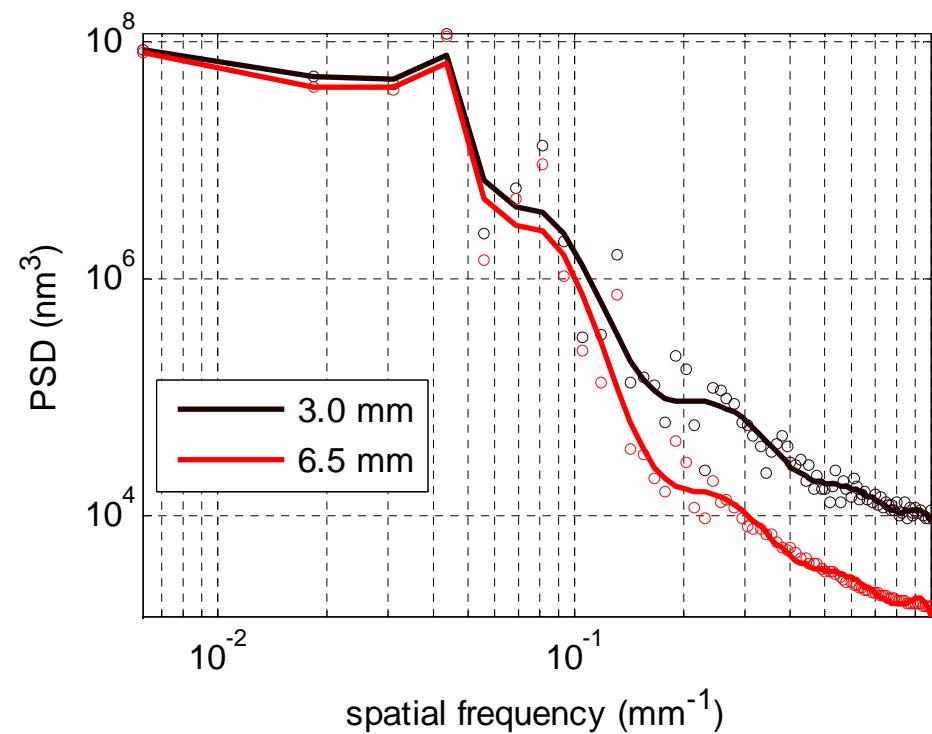
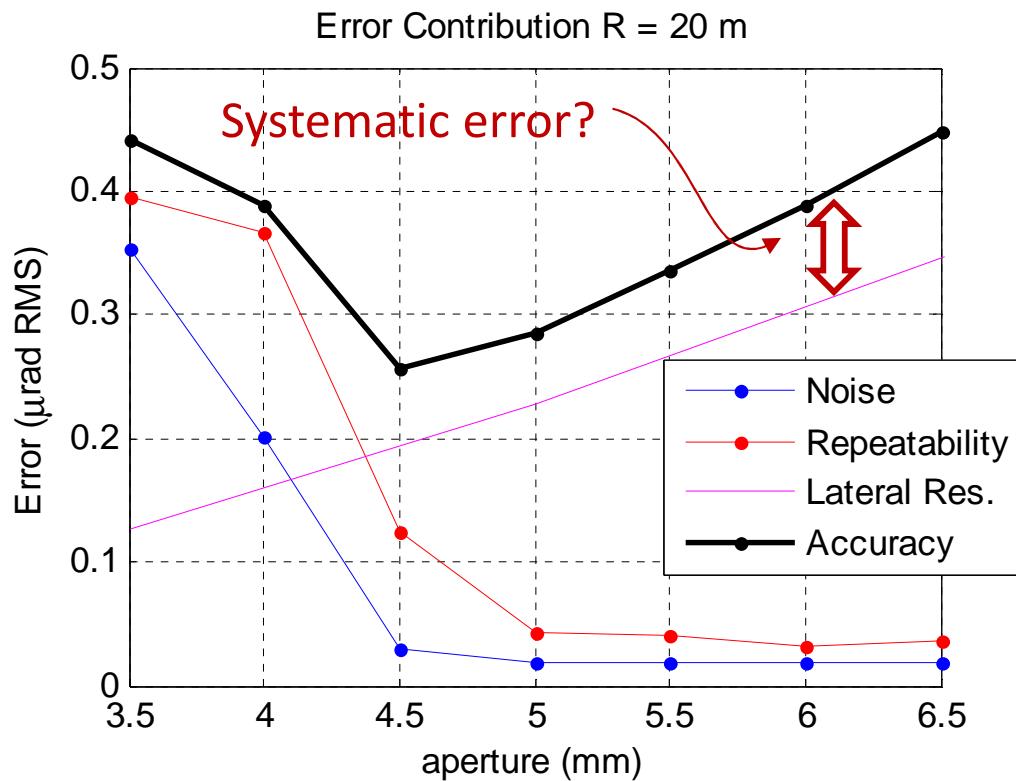
Each reconstruction is based on 54 scans

Residual aberration + periodic subpixel interpolation error found for two different roll positions of the pentaprism.



# Accuracy vs spatial resolution

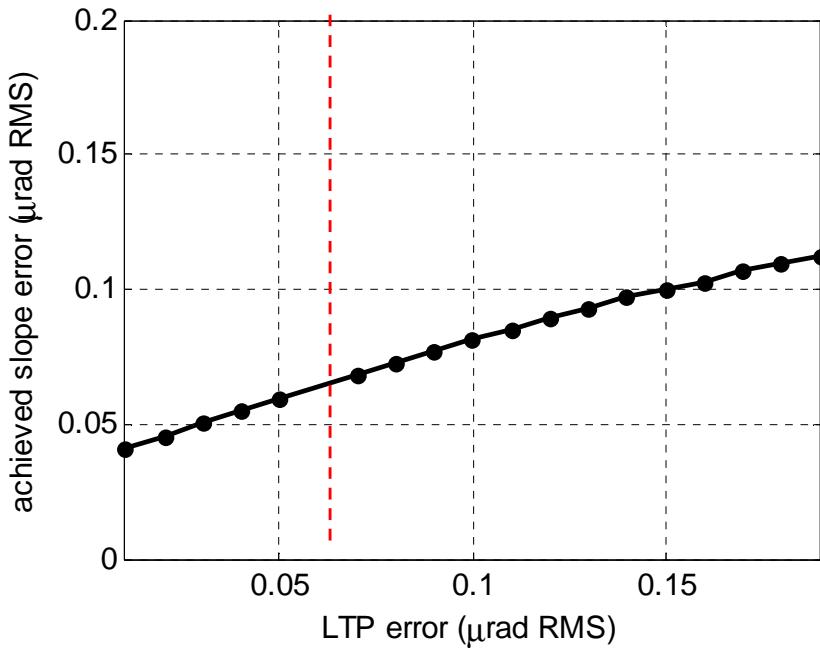
Measurements of the same mirror, using different iris apertures, all compared with a reference measurement at 3 mm iris



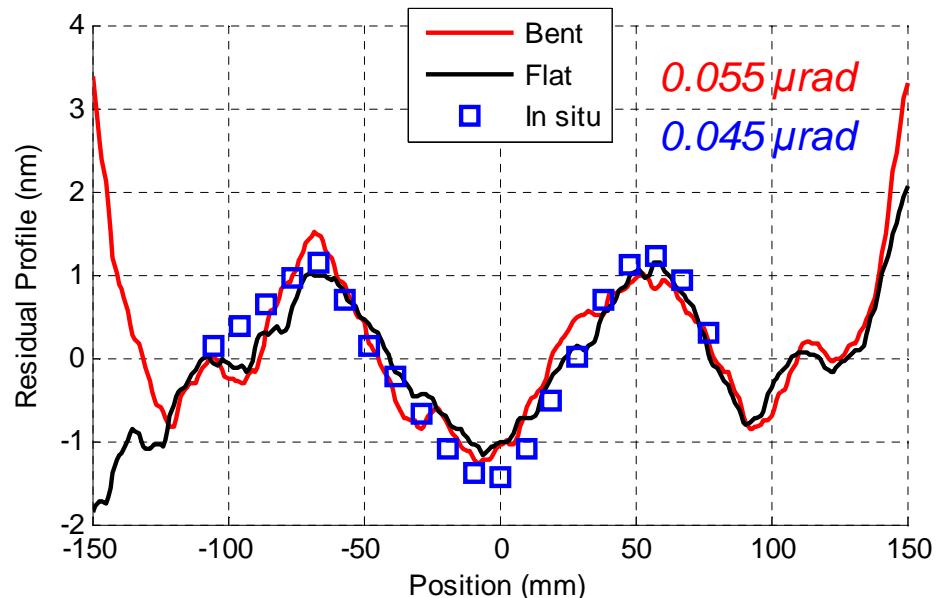
- For small apertures uncertainty is limited by noise and repeatability
- For larger apertures, the error increases, mainly, due to the loss of lateral resolution

# Slope error optimization

For whatever correction technique, accuracy of metrology is a limit to the achievable slope error

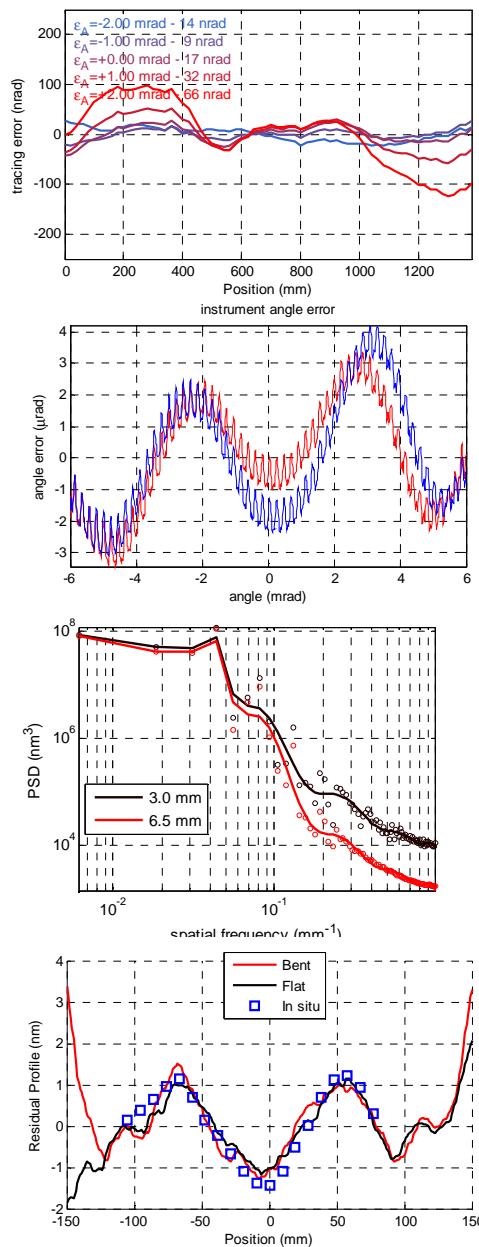


Simulation of the achievable slope error with 2 actuators, as a function of the measurement error.



Mirror figure measured by the pencil beam method matches the profile optimized to 55 nrad at the Alba-NOM 2 years ago.

# Conclusions



*Positioning error correction (LUT) and accurate pentaprism allow reducing the bench induced error to the few nanoradian*

*The usage of redundant-independent datasets allow an accurate modeling of the optics induced error.*

*Using them, also allows reducing the iris aperture, to increase spatial resolution preserving accuracy.*

*The measurements provided by the NOM are accurate enough to optimize the mirror figure to nanometer accuracy*

# Acknowledgements

<i>Computing and Controls</i>	<b>Zbigniew Reszela</b>
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	<b>Sergi Pusó</b>
<i>Algorithms</i>	<b>Juan Campos (UAB)</b>
<i>Engineering</i>	<b>Claude Ruget (CRC)</b>
	<b>Carles Colldelram</b>
	<b>Ricardo Valcárcel</b>
	<b>Jordi Iglesias</b>
<i>Technicians</i>	<b>José Ferrer</b>
	<b>David Calderón</b>
	<b>Pablo Jiménez</b>
<i>Administration</i>	<b>Laura Campos</b>
<i>XALOC beamline</i>	<b>Jordi Juanhuix</b>

Thank you for your attention